IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant:

Shiva Prakash

Title:

Atomic Force Microscopy Measurements Of Contact Resistance And Current-

Dependent Stiction

Serial No.

New – Divisional of Serial No. 10/202,439 filed 07/23/2002

Filing Date:

Herewith

Prior Art Unit:

2856

Prior Examiner

R. Raevis

Atty Docket:

061450/0304609 (FID-101-D5)

MAIL STOP: Patent Applications Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

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Date of Deposit: July 3, 2003

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INFORMATION DISCLOSURE STATEMENT

Applicant submits herewith patents, publications or other information of which Applicant is aware which are believed to be material to the examination of this application and in respect of which there may be a duty to disclose in accordance with 37 CFR 1.56.

The filing of this information disclosure statement shall not be construed as a representation that a search has been made (37 CFR 1.97(g)), nor as an admission that the information cited is, or is considered to be, material to patentability, nor an admission that no other material information exists. The filing of this information disclosure statement shall not be construed as an admission against interest in any manner. Notice of January 9, 1992, 1135 O.G. 13-25, at 25.

The references cited herein were cited in the parent application Serial No. 10/202,439 filed July 23, 2002, and therefore copies are not included.

Respectfully submitted

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INFORMATION DISCLOSURE CITATION PTO-1449				Atty Docket: 061450/0304609 FID-101-D5 Applicant: S. Prakash		Serial No. to be assigned		
Submitted: July 3, 2003				Filing Date: Herewith		Prior Group Art Unit: 2856		
U.S. PATENT APPLICATIONS								
EXAMINER'S INITIALS	PATENT NO.	DATE	NAME		CLASS	SUBCLASS	FILING	DATE
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		FORE	IGN PATI	ENT DOCUMENTS		3.84		
EXAMINER'S INITIALS	PATENT NO.	DATE		COUNTRY		SUBCLASS	Transl	ation
					CLASS		Yes	No
	,							
	OTHER DOCU	I JMENTS (Incl	uding Au	thor, Title, Date, Perti	nent Page	s, Etc.)		
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			ų.					
			<u> </u>				<u> </u>	
EXAMINER				DATE CONSIDERED				

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance <u>and</u> not considered. Include copy of this form with next communication to applicant.